

## Special Issue

# MEMS/NEMS Sensors and Actuators

### Message from the Guest Editors

After the rise of MEMS/NEMS devices in the 1970s, the field of MEMS/NEMS sensors and actuators has grown immensely. Beginning in the 21st century, MEMS/NEMS sensors and actuators have been industrialized and applied not only to consumer markets such as mobile phones and games, but also to intelligent manufacturing, robots, aerospace and other fields. Compared with traditional machinery, MEMS/NEMS technology has the characteristics of being miniaturized, intelligent, multifunctional, highly integrated and suitable for mass-manufacturing processes. This Special Issue seeks to showcase research papers, communications, and review articles that focus on: (1) Novel structural designs of MEMS/NEMS sensors and actuators, (2) Improved fabrication, packaging process and circuit design based on all kinds of MEMS/NEMS products, (3) New sensitive materials committed to a wider range of applications, such as polysilicon, graphene, carbon nanotubes, etc., (4) New developments of applying MEMS/NEMS sensors and actuators including, but are not limited to, MEMS/NEMS pressure sensors, accelerometers, gyroscopes and microphones with capacitive, resonant, piezoelectric and piezoresistive mechanism.

### Guest Editors

Prof. Dr. Yulong Zhao

School of Mechanical Engineering, Xi'an Jiaotong University, Xi'an 710049, China

Dr. Qi Zhang

State Key Laboratory for Manufacturing Systems Engineering, Xi'an Jiaotong University, Xi'an 710049, China

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Editorial Office  
MDPI, Grosspeteranlage 5  
4052 Basel, Switzerland  
Tel: +41 61 683 77 34  
[micromachines@mdpi.com](mailto:micromachines@mdpi.com)

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### Editor-in-Chief

Prof. Dr. Ai-Qun Liu

1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

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